

Title (en)
MICROMECHANICAL COMPONENT WITH REAR VOLUME

Title (de)
MIKROMECHANISCHES BAUELEMENT MIT RÜCKVOLUMEN

Title (fr)
COMPOSANT MICROMÉCANIQUE AVEC VOLUME POSTÉRIEUR

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Application
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Abstract (en)
[origin: WO2010009934A1] The invention relates to a micromechanical component or a method for manufacturing such a component, wherein a cavity (270) is produced in the substrate starting from an opening (215) at the rear of a monocrystal semiconductor substrate (200). The process used for this purpose is controlled in connection with the monocrystal semiconductor substrate used such that a largely rectangular cavity is formed.

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Citation (search report)
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